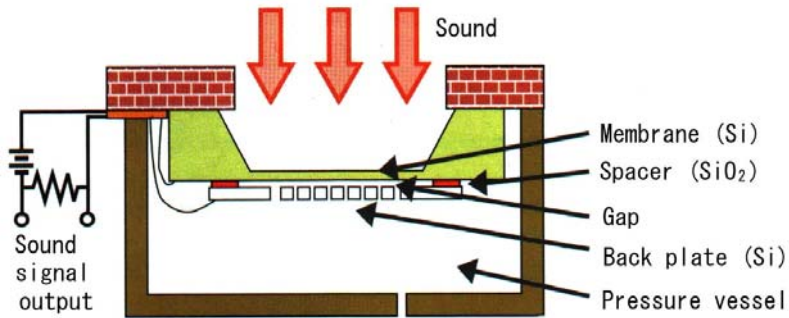


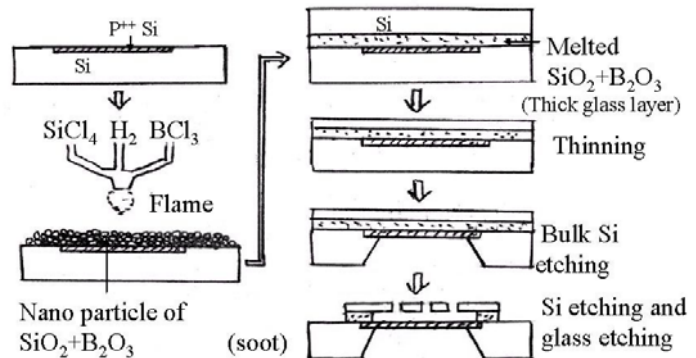
MEMS Microphone (Tohoku Univ. — NHK — Panasonic)



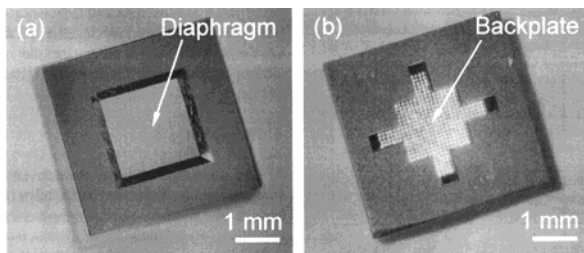
Structure



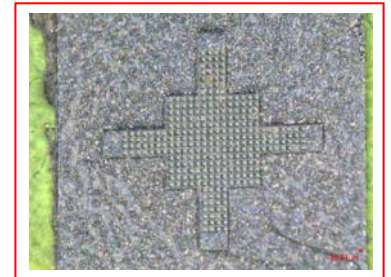
TV program



Fabrication process



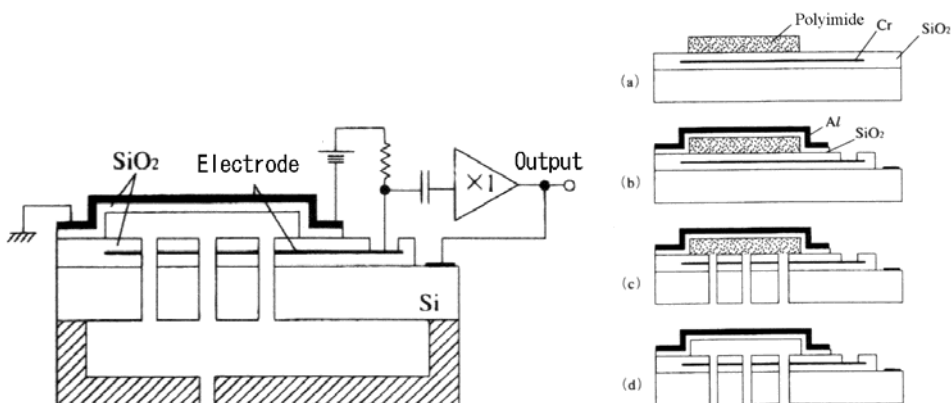
Photograph of chip



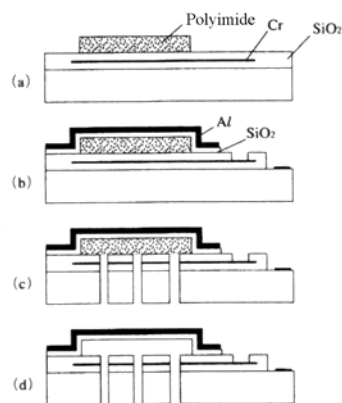
Reference : T.Tajima, T.Nishiguchi, S.Chiba, A.Morita, M.Abe, K.Tanioka, N.Saito and M.Esashi, High-performance Ultra-small Single Crystalline Silicon Microphone of an Integrated Structure, Microelectronic Engineering, 67-68 (2003) pp.508-519

Driven Shield MEMS Microphone

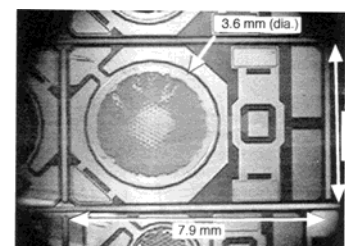
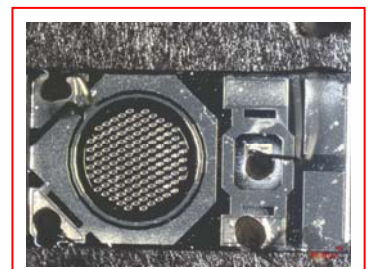
(Tohoku Univ. — Matsushita Communication Industry)



Structure



Fabrication process



Photograph

Reference : M.Ikeda, N.Shimizu and M.Esashi, Surface Micromachined Driven Shielded Condenser Microphone with a Sacrificial Layer Etched from the Backside, Tech. Digest of the Transducers' 99, (1999) pp.1070-1073